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Applicant(s)

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## U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date
C	AA	5,144,833	09/08/92	AMER et al.	250	306	
	AB	5,245,863	09/21/93	KAJIMURA et al.	250	306	
	AC	5,345,816	09/13/94	CLABES et al.	250	306	
	AD	5,347,226	09/13/94	BACHMANN et al.	-	-	
↓	AE	5,445,008	08/29/95	WACHTER et al.	-	-	
	AF						

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-Class	Trans-lation
	AL						Yes No
	AM						Yes No

## OTHER (Including Author, Title, Date, Pertinent Pages, etc.)

C	AR		"Responsive Gels: Volume Transitions I", edited by K. Dusek with contributions by M. Havsky, H. Inomata, A. Khokhlov, M. Konno, A. Onuki, S. Saito, M. Shibayama, R.A. Siegel, S. Starodubtzev, T. Tanaka, V.V. Vasilivskaya. Springer-Verlag Berlin Heidelberg New York London Paris Tokyo Hong Kong Barcelona Budapest				
C	AS		"Thermal and ambient-induced deflections of a scanning force microscope cantilevers" by T. Thundat, R.J. Warmack, G.Y. Chen and D.P. Allison, Appl. Phys. Lett., Vol. 64, No. 21, 23 May 1994, pp. 2894-2896				
C	AT		<del>"Protecting Amplifiers from High-Voltage Inputs,"</del> Sensors The Journal of Applied Sensing Technology, Vol. 11 No. 5 May 1994, pp. 8-9				
C	AU		"Optical and Infrared Detectors" edited by R.J. Keyes with contributions by R.J. Keyes, P.W. Kruse, D. Long, A.F. Milton, E.H. Putley, M.C. Teich and H.R. Zwicker, Springer-Verlag Berlin Heidelberg New York 1977, pp. 71-100				
C	AV		"Observation of a chemical reaction using a micromechanical sensor" by J.K. Gimzewski, Ch. Gerber, E. Meyer and R.R. Schlittler, Chemical Physics Letters, Volume 217, number 5.6, January 28, 1994, pp. 589-594				

Examiner

Fields

Date Considered

9-92

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 Include copy of this form with next communication to Applicant.